

Demonstration of Ultra Low Dissipation Optomechanical Resonators on a Chip

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Radiation-pressure coupling of optical and mechanical degree of freedom of micro- and nano-mechanical systems gives rise to a host of optomechanical phenomena which are of interest for a range of applications and in particular provide a route to the quantum regime of mesoscopic mechanical oscillators. While individually ultra-low loss optical and mechanical resonators have been attained, a prime challenge in the emerging field of cavity optomechanics has however been to realize systems which *simultaneously* maximize optical finesse and mechanical Q . Here we demonstrate for the first time independent control over both mechanical and optical degree of freedom within *one and the same* on-chip device. Shaping the mechanical properties of ultra-high finesse optical microcavities enables novel optomechanical resonator geometries with mechanical Q -factors on par with the best values achieved to date. Equally important, we provide the first direct observation of mechanical normal mode coupling in micromechanical systems, allowing a quantitative understanding of mechanical dissipation, which may be of relevance across a wide range of micro- and nanomechanical oscillators, for which a detailed understanding of dissipation is lacking.

Over the past years it has become experimentally possible to study the coupling of optical and mechanical modes via radiation pressure, which gives rise to a diverse set of long anticipated optomechanical phenomena[1] such as radiation pressure driven oscillations[2] and back-action cooling[3, 4, 5]. Moreover, this coupling can be exploited to perform highly sensitive measurements of displacement[6] which may enable to observe radiation pressure quantum backaction[7] or related phenomena. While recently impressive progress has been made in creating experimental settings in which these radiation pressure phenomena can be studied[3, 4, 5, 8, 9, 10], a prime challenge concerns attaining simultaneously high optical finesse and high mechanical Q -factors. Nearly all approaches[3, 4, 8, 9, 10] so far have combined traditional cm-sized optical elements (mirrors) with micro- or nanoscale mechanical oscillators which simultaneously act as a mirror. The unavoidable compromise between size, reflectivity and mechanical Q -factor of the micro-mirror, however, renders it very difficult to obtain high optical finesse and high mechanical Q as it does not allow independent control of optical and mechanical degrees of freedom. Thus, although remarkably high mechanical Q -factors at low frequencies have been obtained[10], this approach has so far not succeeded in combining mechanical Q -factors comparable to those achieved in the field of NEMS and MEMS[11, 12, 13, 14] with the best values of optical finesse ($> 10^6$)[15, 16]. But exactly the combination of both is important for applications such as low loss, narrow-band "photonic clocks" and indispensable for fundamental studies aiming at approaching and detecting quantized motion in mesoscopic optomechanical systems.

Here we show for the first time entirely independent control over both optical and mechanical degree of freedom in *one and the same* microscale optomechanical device. We demonstrate monolithic silica spoke-resonators comprising a toroidal boundary which allows ultra-high

optical finesse ($> 10^6$)[15] rivaling the best values obtained in Fabry-Perot cavities[16]. Independent control of their mechanical properties using a spoke-design leads to unprecedented mechanical quality factors of 50,000 above 20 MHz at room temperature—on par with the best published values of strained silicon nitride nanoresonators[17] as well as with radial contour-mode disk resonators[12] in this frequency range. The spokes-design allows these Q -factors in high frequency modes for which resolved sideband cooling[18] (prerequisite for ground state cooling[19, 20] and for measurements beyond the standard quantum limit using "two transducer" readout[21] which can also generate squeezed states of mechanical motion[22]) is possible. Yet, it also allows tuning of the mechanical modes to lower frequencies resulting in increased displacement amplitudes which could eventually enable the observation of radiation pressure quantum back-action[7]. Moreover, the first demonstration of curve veering[23]—an avoided crossing between mechanical modes, equivalent to normal mode coupling—and the concomitant geometry dependence of clamping losses allows a quantitative understanding of mechanical dissipation, which may be of relevance across a wide range of micro- and nanomechanical oscillators, for which a detailed understanding of dissipation is lacking.

Starting point of our analysis are toroidal silica microcavities[24] that intrinsically combine ultra-high Q -optical whispering gallery modes with around 20 mechanical modes in the 0-100 MHz range which are observable in an interferometric readout using the structure's optical modes (see methods). Recent work has shown that the intrinsic coupling of optical and mechanical modes of optical microcavities[25] via radiation-pressure can give rise to the effect of dynamic backaction, which allows realization of narrow bandwidth photonic oscillators[2] or photonic RF down-converters[26] as well as radiation pressure cooling of a mechanical oscillator[5]. The radial breathing mode (cf. Fig. 1a) in particular is amenable

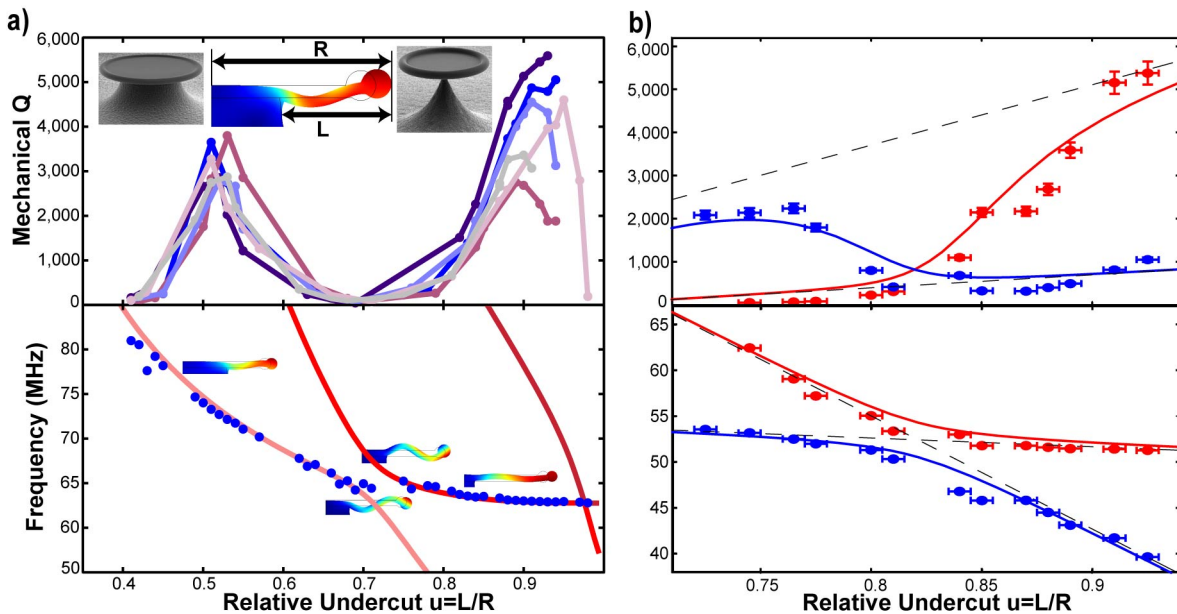


FIG. 1: **Observation of mechanical mode coupling.** **a)** Mechanical Q -factors (upper panel) and frequencies (lower panel, where solid lines denote results of an FEM simulation) of the radial breathing mode (inset) for varying relative undercut $u = L/R$. The Q -factors were found to be remarkably reproducible for six different samples and strongly geometry dependent due to intermode coupling. **b)** Q -factors (upper panel) and frequencies (lower panel) of radial breathing mode and a flexural mode of one toroid reveal an avoided crossing confirming that the dispersion lines of both modes do not cross. The mode patterns (radial and flexural modes) hybridize when approaching the coupling region while the corresponding mode patterns have switched the dispersion curve when decoupling from each other. A coupled harmonic oscillator model (solid lines: coupled Q -factors and frequencies; dashed lines: bare Q -factors and frequencies) allows an excellent fit to the data.

to cooling as it has low effective mass ($\approx 10^{-11}$ kg) and with its high frequency enabled the first demonstration of resolved sideband cooling of a micromechanical oscillator[18].

To understand the mechanical Q -factors of silica microtoroids which have remained completely unexplored so far, we begin with a study of mechanical dissipation in microtoroids and show that clamping losses are the dominant source of damping—strongly influenced by mechanical mode coupling[23]. It is precisely this phenomenon that gives us a detailed understanding of mechanical losses and allows for a subsequent strong reduction of dissipation.

In order to assess the contribution of clamping losses in the mechanical modes of silica microtoroids, the diameter of the silicon pillar holding the silica structure (cf. Fig. 1a) is varied. To this end consecutive XeF_2 etching cycles, undercutting the silica structure but leaving the silica itself unaffected, are applied. Thus, the relative undercut u defined as the ratio between length L of the free standing membrane and the radius R of the disk (cf. Fig. 1a) can be controlled. Intuitively, one would expect higher Q -factors for larger undercut due to reduced clamping area. The dependence of the measured Q -factors of the radial breathing mode (RBM) on the relative undercut is depicted in Fig. 1a). Interestingly,

the Q -factors of six different microresonators of similar size show a strong oscillatory dependence on the relative undercut which contradicts the simple intuition of smaller losses for smaller clamping areas. The depicted Q -factors reach a first peak of around 4,000 ($u \approx 0.5$), drop to less than 100 ($u \approx 0.7$) and, after rising again to above 5,000 ($u \approx 0.9$), the Q -factors degrade for small pillar diameters, i.e. for $u \rightarrow 1$. Moreover, this behaviour is remarkably reproducible for the different samples individually fabricated. A plot of the measured frequencies along with an FEM simulation (see methods) of the toroid’s radially symmetric mechanical modes depicted in Fig. 1a) shows excellent agreement of measured and simulated frequencies. Furthermore, an avoided crossing between the RBM and a flexural mode of the toroid is predicted. Exactly in the region in which both modes according to FEM simulations couple and hybridize, the Q -factor of the RBM is found to be strongly reduced. This phenomenon of an avoided crossing between mechanical modes upon variation of a structure’s geometry was predicted by Mindlin already in 1951[23] but, to the authors’ best knowledge, has never been reported in the context of micro- or nanomechanical oscillators. A more precise optical measurement (see methods) revealing further mechanical modes confirms the avoided crossing, as depicted in Fig. 1b) where the measured frequencies and

the corresponding Q -factors of both the radial breathing mode and a flexural mode for a sample with varying relative undercut are shown. As expected by the FEM simulations the frequencies of both modes approach each other but do not cross. During the avoided crossing the mode patterns hybridize and eventually swap their dispersion lines. Also the Q -factors of both modes approach each other during the crossing as depicted in Fig. 1b).

This distinctive behaviour—which so far has never been reported in micromechanical systems—can be well explained with a generic model of two coupled harmonic oscillators $x_{r/f}$, representing the bare radial (r) and flexural (f) mode, with angular frequencies $\Omega_{r/f}$ and damping rates $\Gamma_{r/f}$. An offset of the torus from the equatorial plane of the silica disk[27] as well as the single-sided clamping of the disk to the silicon pillar give rise to an appreciable coupling rate g between both modes. The coupled eigenvalues of such a system read

$$\lambda_{\pm} = \frac{\Omega_r + \Omega_f}{2} + i\frac{\Gamma_r + \Gamma_f}{4} \pm \sqrt{\left(\frac{\Omega_r - \Omega_f}{2} + i\frac{\Gamma_r - \Gamma_f}{4}\right)^2 + \frac{g^4}{4\Omega_r\Omega_f}} \quad (1)$$

and thus the coupled eigenfrequencies $\nu_{\pm} = \text{Re}(\lambda_{\pm})/2\pi$ and Q -factors $Q_{\pm} = \text{Re}(\lambda_{\pm})/2\text{Im}(\lambda_{\pm})$ can be calculated. Assuming a linear dependence of the bare frequencies $\Omega_{r/f} = \Omega_{r/f}^{(0)} + \Omega_{r/f}^{(1)}u$ and Q -factors $Q_{r/f} = Q_{r/f}^{(0)} + Q_{r/f}^{(1)}u$ on the undercut u , these can be used to asymptotically fit the data (cf. Fig. 1b). Using the values obtained from this first fit, only g remains as free parameter in equation (1). A least square fit to both the measured frequencies and Q -factors yields a coupling rate of $g/2\pi = 14$ MHz, more than one order of magnitude larger than the damping rates $\Gamma_{r/f}$. The corresponding coupled frequencies ν_{\pm} and Q -factors Q_{\pm} match the data remarkably well (cf. Fig. 1b) confirming that indeed both modes behave as two coupled harmonic oscillators giving rise to an avoided crossing. Similar coupled oscillator models apply, e.g. for cavity or circuit QED where a two level system (atom[28], quantum dot[29] or cooper pair box[30]) can couple to the modes of an optical cavity[28, 29] or a microwave resonator[30]. The data presented here, however, manifests the first direct observation of normal mode coupling of two different mechanical modes within a micromechanical device.

For the Q -factor of the radial breathing mode the avoided crossings are detrimental. The hybridization with the low- Q flexural modes leads to strongly increased dissipation due to the enhanced displacement amplitudes in the clamping area. Drawing on the quantitative power of FEM simulations (see methods), it is indeed possible to show that the displacement amplitudes at the pillar

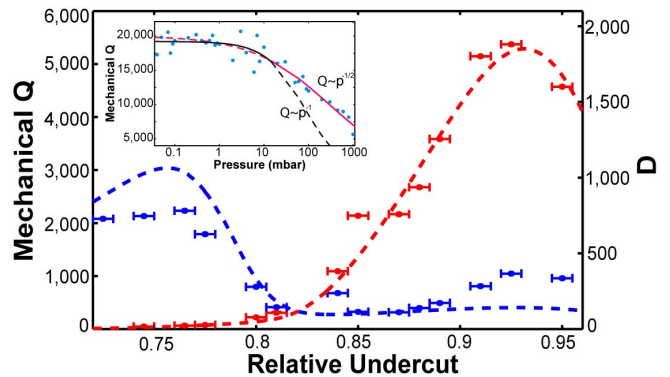


FIG. 2: **Linear relation between D and measured Q -factors** Mechanical Q -factors (dots with error bars) and corresponding simulated D values (dashed lines) for the radial breathing and a flexural mode of an on-chip toroid show an approximately linear relation in the parameter range depicted. In the next step we use the knowledge of this parameter to find optimized cavity geometries which exhibit a strong increase in D . Inset: Mechanical Q -factors depending on the background gas pressure. Below 1 mbar the gas damping contribution becomes negligible. The black and red lines correspond to fits in the molecular ($Q \propto p^{-1}$) and viscous ($Q \propto p^{-1/2}$) gas damping regime.

strongly influence the mechanical Q -factor. In order to study—and elucidate—the role of clamping losses the parameter D , defined as:

$$D = \left(\frac{c\rho}{E_{\text{mech}}} \Omega \int_{A_p} |\Delta z(r)|^2 dA \right)^{-1} \quad (2)$$

is introduced, where E_{mech} is the total energy stored in the oscillator, ρ is the density of silicon, and c the speed of sound in silicon, $\Delta z(r)$ is the out of plane oscillation amplitude at position r , and the integration extends over the clamping area A_p . D is exactly the mechanical quality factor that is expected if the clamping area A_p is modeled as a membrane, radiating away acoustic energy with a power of $P = c\rho\Omega^2 \int_{A_p} |\Delta z(r)|^2 dA$. This acoustic loss leads to a Q -factor of $D = \left(\frac{P}{\Omega E_{\text{mech}}} \right)^{-1}$ as given by equation (2).

Strikingly, D shows a remarkable correlation with the measured Q -factors. In Fig. 2 the Q -factors measured for two different modes of one microresonator are shown together with the simulated values of D . The Q data can be remarkably well reproduced showing that the Q -factors ranging from a few hundred up to 6,000 exhibit direct proportionality to D . This unambiguously shows that the Q -factors are clamping loss limited. Note that these, and all following measurements were performed in a vacuum chamber ($p < 1$ mbar) to fully eliminate the possible influence of gas damping (cf. Fig. 2). Besides explaining the origin of the mechanical dissipation

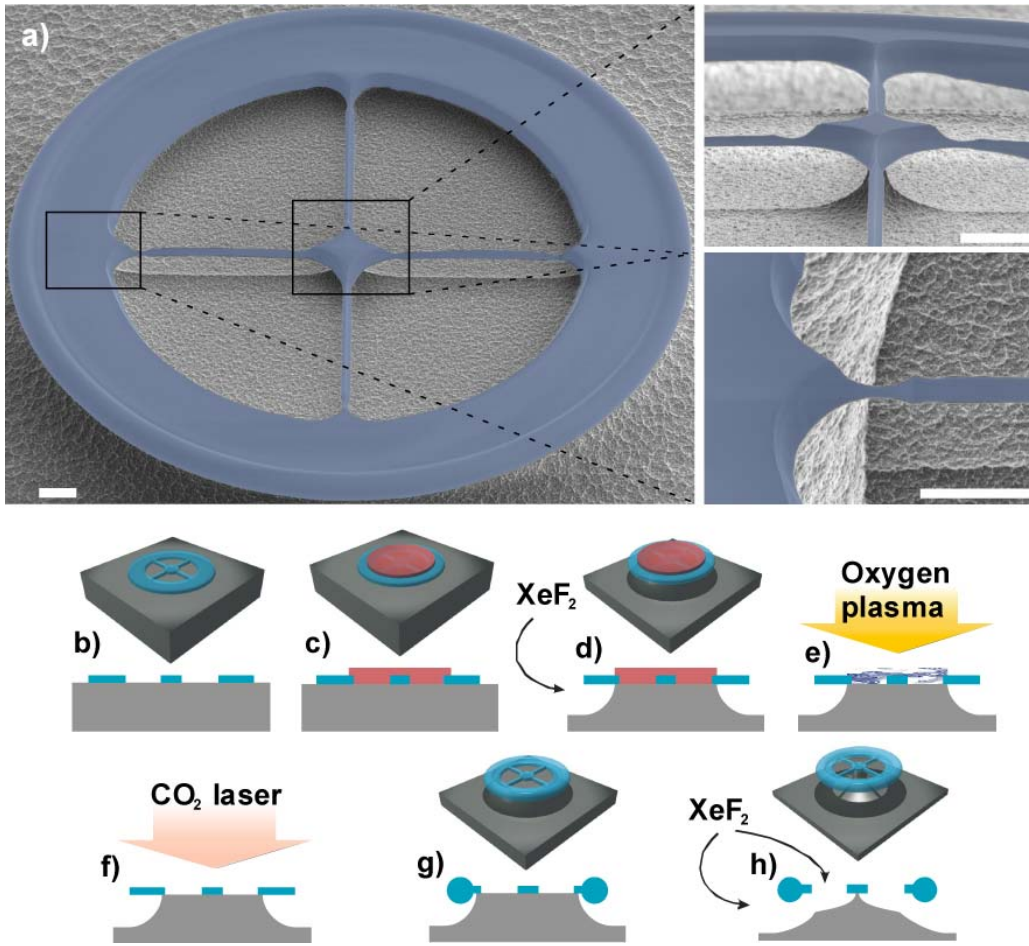


FIG. 3: **Novel optomechanical spokes-resonators** a) SEM images of on-chip optomechanical resonators consisting of a toroidal boundary supported by four spokes (scale bar: $5 \mu\text{m}$ in each panel). The optomechanical system (outer torus) is connected to the silicon chip via silica bridges, decoupling its radial motion from the clamping area in the center of the disk. For the depicted design mechanical Q -factors up to 50,000 are obtained at frequencies exceeding 20 MHz at room temperature. b)-h) Fabrication process of ultra low dissipation optomechanical resonators on a chip. First the spokes pattern is defined in the oxide layer of an oxidized silicon chip by UV lithography and HF wet-etching (a). A protective layer of photoresist (b) covers the spokes while the structure is under-etched from the sides using isotropic silicon dry etch (c). The photoresist is removed (d) and the laser reflow (e) creates the ultra-smooth toroid microcavity (f) while the spokes remain undamaged as their contact to the silicon pillar provides a sufficient heat sink. A final etching step creates a sub-micron scale needle support of the structure without affecting the ultra-high optical Q -factors (g).

of different modes and proving that plainly reducing the clamping area to a minimum is not sufficient for optimized Q -factors (cf. Fig. 1a) the parameter D moreover allows *a-priori* modelling of the oscillator's mechanical quality. This constitutes a powerful, direct tool to design high- Q mechanical oscillators, which we have used to device the novel structures below.

One such geometry is shown in Fig. 3a) consisting of a toroid resonator with four spokes connecting it to a sub-micron scale silicon support. Incorporation of the silica spokes into a toroidal micro-resonator is possible by following the fabrication steps as shown in Fig. 3b)-h). Importantly, the design allows independent control of the spokes' width, length and position for any ma-

ior and minor diameter of the optical toroid microcavity. Using the aforementioned FEM model of the Q -factors, i.e. maximizing D , the geometry can be chosen such that the discrete eigenfrequencies of the spokes decouple the toroid's radial motion from the center of the silica disk, strongly mitigating clamping losses.

The experimental implementation confirms the predictions based on the dependence of the Q -factors on D . Fig. 4 shows a plot of the measured Q -factors depending on the simulated values of D for several different samples of vastly different geometries with and without spokes. Note that over the range of Q -factors which covers three orders of magnitude, one still finds a monotonous dependence of the mechanical quality factors on D : increasing D results in higher mechanical Q -factors. Thus, using

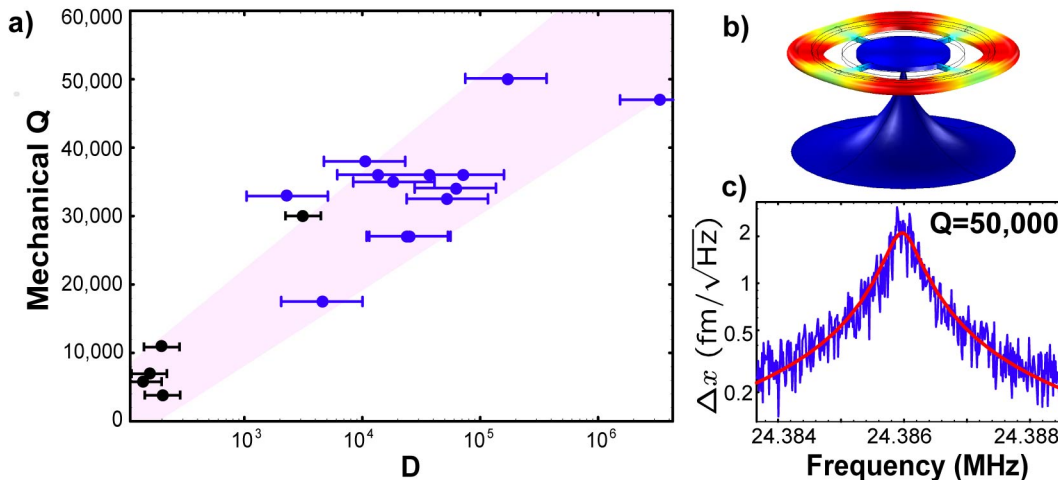


FIG. 4: **Mechanical Q -factors of spokes-resonators** a) Measured mechanical Q -factors versus simulated D values for the RBM of micro-resonators with spokes (blue dots) and different modes of an optimized high- Q toroid (black dots) showing a monotonous relation between D and Q covering three orders of magnitude in quality factor. The horizontal error bars (6dB for spokes resonators, 3dB for toroids) mark the uncertainty in the calculation of D due to deviations of the actual microresonator geometry from the geometry used in the simulation (inferred by SEM imaging). Note that the datapoints correspond to vastly different geometries as well as different modes and still a monotonous relation between D and mechanical quality factors remains valid. b) FEM simulation of the radial breathing mode of a spokes-microresonator. c) Displacement spectrum of a spokes resonator with a mechanical Q -factor of $Q = 50,000$ at 24.4 MHz—on par with the best published values at room temperature.

the spokes design the mechanical Q -factors can indeed be increased as predicted by the FEM model. Moreover, a remarkably high level of mechanical Q of 50,000 at a frequency of 24 MHz (at room temperature) is achieved, which rivals the best published values at this frequency range and at room temperature (as given by strained silicon nitride nanostrings[17] and radial contour-mode disk resonators[12]) allowing for the first time to combine ultra-high optical finesse and the best reported mechanical Q -factors within one and the same device.

It is important to note that the highest Q -factor of 50,000 was achieved already in the first experimental run with optimizing neither spokes length nor width or position. Even for values as high as 50,000 the mechanical Q -factors are found to strongly depend on the relative undercut which indicates that they are still dominated by clamping losses. According to FEM simulations an experimentally feasible optimized design leads to values of D which are more than two orders of magnitude higher than the value corresponding to a Q -factor of 50,000. Thus, with an optimized spokes design clamping losses can be further reduced and significant improvements beyond the Q -factors reported here should be possible. It is noted that ultimately loss mechanisms other than clamping losses could become important. As, however, estimations for silica show that thermoelastic damping[31, 32] should not limit the Q -factors to values below 100,000 even at room temperature values approaching 100,000 are indeed realistic.

It is emphasized that the optical properties of the toroid

microresonators are not affected by the optimized mechanical design. The CO_2 laser assisted reflow process[24] creating the surface tension induced surface finish of the silica toroid can still be applied. As a result, the thermal bistability and optical mode-splitting[33], salient features of ultra high- Q silica microtoroids[15], can be observed in the novel spokes-microresonators. At the same time, the mechanical design is not adversely affected by the laser reflow process, even for very small spokes (cf. Fig. 3). Thus, optical and mechanical properties of microtoroidal optomechanical resonators can be decoupled and optimized independently. The mechanical frequencies and Q -factors are controlled by choosing appropriate spokes dimensions without affecting the choice of minor and major diameter of the toroid defining its optical frequencies and finesse[15].

In summary, we presented novel micron-scale on-chip optomechanical resonators that for the first time allow independent control of optical and mechanical degrees of freedom within one and the same device. Avoided crossings of mechanical modes (curve veering[23]) were observed which enabled a detailed understanding of mechanical dissipation, allowing the design of optomechanical systems combining mechanical Q -factors of 50,000, on par with the best published results in the frequency range above 20 MHz, with ultra-high optical finesse. Given the theoretical predictions, Q -factors up to 100,000 could be feasible via further optimization. The novel system offers improved performance for applications such as realizing narrow band filters and narrow line-width radia-

tion pressure driven "photonic clocks". Equally important, the studied aspects of geometry dependent mechanical dissipation via mode coupling and clamping losses can be of broad interest and could also be applicable to a wide range of other micro- and nanomechanical oscillators such as carbon nanotubes[34, 35] or graphene sheets[36] whose mechanical properties are not fully understood. Indeed mechanical mode coupling also pertains to nanomechanical beam resonators[37].

Due to the decoupling of optical and mechanical degrees of freedom, i.e. the tuning of mechanical frequencies and Q -factors independent from the system's optical properties, the resonator constitutes a powerful experimental setting for cavity optomechanics[38] combining the best mechanical Q -factors with ultra-high optical finesse within one device. This property is highly advantageous in studies which seek to demonstrate quantum signatures of a mesoscopic object[7, 39]. For example, the ratio of displacement spectral density provided by radiation pressure back-action and the thermal noise spectral density is given by[40]: $S^{\text{ba}}/S^{\text{th}}[\Omega] = \frac{4\alpha^2}{1+4\Omega^2/\kappa^2} \frac{\hbar Q \mathcal{F}^2}{\lambda(c/n) \pi k_B T m \Omega} P_{\text{cav}}$ ($\alpha = 1$ for a linear cavity and $\alpha = \pi$ for a ring-cavity). For cryogenic operation at temperature $T = 1.6$ K (which is currently set up in our laboratory) and the moderate parameters $\lambda = 1 \mu\text{m}$ (wavelength), $m = 10$ ng (effective mass), $\Omega/2\pi = 20$ MHz (mechanical frequency), $Q = 50,000$ (mechanical quality factor) and finesse of $\mathcal{F} = 100,000$ (the cavity bandwidth κ for a toroidal cavity is given by $\kappa = c/nR\mathcal{F}$, where a cavity radius of $R = 40 \mu\text{m}$ and a refractive index of silica of $n = 1.4$ are assumed) this expression reaches unity already at an intra-cavity power P_{cav} as low as $P_{\text{cav}} = 210 \mu\text{W}$. Thus, radiation pressure quantum back-action—which so far has remained experimentally inaccessible—is within reach. Moreover, given the radiation-pressure cooling rates of $\Gamma_c = 1.56$ MHz already achieved in silica microtoroids[18] and a starting temperature of $T = 1.6$ K mechanical Q -factors of 50,000 would allow to laser cool the RBM in the resolved sideband regime to an occupation number of $n = \frac{1}{Q} \frac{k_B T}{\Gamma_c} \approx 0.4$, below unity.

METHODS

Optomechanical monitoring

To monitor the mechanical modes' thermal noise, laser light is coupled to the high- Q optical whispering gallery mode of the silica toroid using a tapered optical fibre[24, 42]. An external cavity diode laser is locked detuned by approximately half the optical line-width κ with respect to a cavity resonance ω_0 . Thus, the small, thermal fluctuations Δx of the cavity radius cause changes in the optical path-length which imprint themselves linearly into an amplitude modulation ΔP of the power P

transmitted by the cavity, i.e. $\Delta P \propto \Delta x$.

Spectral analysis of the transmitted power thus allows extracting the mechanical frequencies $\Omega/2\pi$ and dissipation rates $\Gamma/2\pi$ from which the corresponding quality factor $Q = \Omega/\Gamma$ is inferred. To minimize radiation pressure induced back-action, i.e. to rule out any amplification[2] or cooling[5] which would lead to a modification of the natural line-width[5], the laser power used in these measurements is kept at a very low level, well below the threshold for the parametric instability. As an additional check the measurements are always performed both on the red and blue detuned wing of the optical resonance. The Q -factors from both measurements usually agree within less than 5%, indicating negligible radiation pressure backaction. In order to achieve a higher displacement sensitivity allowing to observe further mechanical modes of the microtoroid, an adapted version[18] of the Hänsch-Couillaud polarization spectroscopy[41] using a shot-noise limited (for frequencies > 10 MHz) Nd:YAG laser locked to cavity resonance is employed (cf. Fig. 5). The polarization of the field injected into the taper is chosen such that only a small portion of the cavity (E_{WGM}) while the larger part E_{LO} bypasses the cavity serving as a local oscillator. Analyzing the phase-shift of the field exiting the cavity via a homodyne detection (cf. Fig. 5) a shot-noise limited sensitivity $\sqrt{S_x^{sn}[\Omega]} = \frac{\lambda}{8\pi\mathcal{F}} \sqrt{\frac{\hbar\omega}{P}} \sqrt{1 + 4\Omega^2/\kappa^2}$ of order 10^{-19} m/ $\sqrt{\text{Hz}}$ is achieved (at the frequencies of interest from 10-100 MHz). Thus, not only the radial breathing mode but more than twenty different mechanical

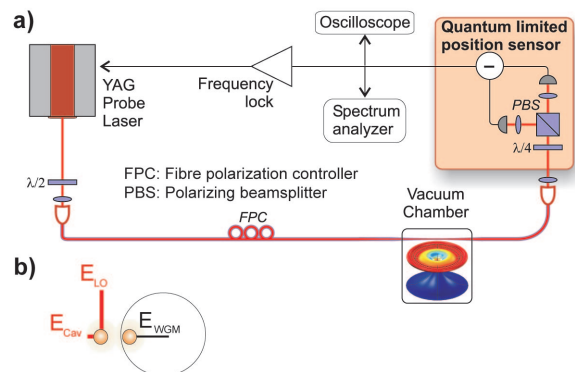


FIG. 5: **Schematic of the Hänsch-Couillaud[41] spectroscopy setup.** A Nd:YAG laser is coupled to the cavity in a vacuum chamber via a tapered fibre (a). The polarization of the field injected into the fibre is adjusted such that only a small fraction of the field matches the polarization of the WGM of the toroid. The larger part of the field bypasses the cavity (b). The transmitted light is sent through a quarter wave plate (a) and a polarization beam splitter is used to separate the polarization components. The difference signal of both ports is monitored and also used to lock the laser to cavity resonance using electronic feedback.

modes of the toroid between 0-100 MHz can be monitored. All observed modes can be identified with the recording mode pattern obtained by FEM simulation with a relative frequency deviation of less than 5%.

FEM simulations

A commercial software package (COMSOL Multiphysics) is used for 3D finite element modelling of the cavity structures. Using fixed boundary conditions at the bottom of the conical silicon pillar, the eigenvalue solver provided by the package calculates the eigenfrequencies $\Omega/2\pi$ and the corresponding stress and strain fields of the meshed structure by diagonalizing its coupled linear equations of motion. Summing over all elements the total mechanical energy E_{mech} of the mode can be calculated. Typically 100,000 elements are used where in the clamping region the characteristic size of an element is of order 200 nm. In order to calculate the parameter D , the squared out of plane displacement amplitude $|\Delta z(r)|^2$ is summed over the plane connecting the silica resonator and the silicon substrate. D can be considered as the ratio of the mode's total energy over the acoustic energy P/Ω which is radiated away per oscillation period by the motion of the clamping area modeled as a membrane emitting at a power of $P = c\rho\Omega^2 \int_{A_p} |\Delta z(r)|^2 dA$.

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